



Art Unit: 2892  
Examiner: Mr. William F. Kraig

In re PATENT APPLICATION of:

Applicant	:	Akira TAKAHASHI	)	
			)	
Serial No.	:	10/798,482	)	
			)	
Filed	:	March 12, 2004	)	<b>AMENDMENT</b>
			)	<b>AFTER</b>
			)	<b><u>FINAL REJECTION</u></b>
For	:	DRY ETCHING METHOD FOR	)	
		SEMICONDUCTOR DEVICE	)	
			)	
Attorney Ref.	:	OKI 414	)	
			)	
				<hr/> September 20, 2010
				<i>41</i>

**Mail Stop AF**  
Director of Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

This is responsive to the Office Action of April 21, 2010, the period for reply to which is being extended to expire on September 21, 2010 by a Petition that is being filed concurrently. A Request for Continued Examination (RCE) is also being filed concurrently to relieve the above-identified application of its finally-rejected status.

A fee of \$ 1300 is also being submitted concurrently. Should this remittance be accidentally missing, however, or should any additional fees be needed, the Director may charge such fees to our Deposit Account number 18-0002.

Please amend the above-identified application as specified on the following pages, and then reconsider the application in view of the Remarks that are presented thereafter.